

Form PTO-1448				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2067	SERIAL NO. 10/624340 Filed Herewith		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Brant A. McClure et al					
				FILING DATE Filed Herewith		GROUP Unknown 2831			
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
/NH/	AA	6,180,481	1/01	DeBoer et al					
	AB	6,218,256	4/01	Agarwal					
	AC	6,204,049	8/00	Selvayappan 6,104,049					
	AD	6,180,447	1/01	Park					
	AE	6,274,428	8/01	Wu					
	AF	6,124,158	9/00	Dauartas et al					
	AG	6,144,060	11/00	Park					
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✓	AJ	6,204,172	9/98	Marah 3/20/2001					
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/NH/	AL	6,242,299	06/01	Hickert					
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
								Yes	No
	AM								
	AN								
	AO								
	AP								
	AO								
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)									
/NH/	AR		A.W. Ott, et al., "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pp. 128-136.						
	AS								
EXAMINER /Nguyen Ha/				DATE CONSIDERED 06/20/2007					
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